

**Clean Copy of Amended Claim 1**

- B1
1. (Amended) An LPCVD apparatus comprising, a container for accommodating an organometallic compound, said compound serving as a raw material; a heating means for heating the container and vaporizing the organometallic compound to obtain a raw material gas; a reactor for accommodating a substrate on which a thin film is precipitated; an exhaust pump for maintaining a low pressure atmosphere within the reactor; and a trap provided on the upstream of the exhaust pump and cooling used raw material gas supplied from the reactor, wherein said trap is provided with honeycomb-structure cylindrical fillers in a flowing passage through which the used raw material flows.

**Copy of New Claim 9.**

- B2
9. (New) The LPCVD apparatus according to claim 1 wherein the honeycomb-structure cylindrical fillers are metal honeycomb-structure cylindrical fillers.